

05-21-2004

Docket: HSJ920040044US1



US Department Of Commerce
Patent & Trademark Office

102750224

To the Honorable Commissioner of Patents and Trademarks: Please record the attached original documents or copy thereof.

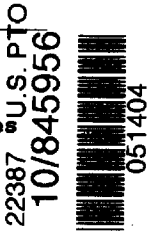
1. Name of conveying party(ies): 2. Name and address of receiving party(ies):

Alexander Driskill-Smith
Hieu Lam
Kim Y. Lee

5/14/04

Name: Hitachi Global Storage Technologies
Netherlands B.V.

Street Address:
Locatellikade 1
Parnassustoren
1076 AZ Amsterdam
The Netherlands



Additional name(s) of conveying
party(ies) attached __Yes XX No

Additional name(s) & address(es) attached?
__Yes XX No

3. Nature of conveyance:

XX Assignment Execution Date: _____

4. Application number(s) or patent number(s):

10845956

If this document is being filed together with a new application, the execution date of the application is: _____

A. Patent Application No.(s)

B. Patent No.(s)

Additional numbers attached? __Yes XX No

5. Name and address of party to whom
correspondence concerning document
should be mailed:

Name: Hitachi Global Storage Technologies
Internal
Address: Intellectual Property Law
Street
Address: 5600 Cottle Road, Dept. NHGB/014-2,
San Jose, California 95193

6. Total Number of applications and patents
involved: One

7. Total fee (37 CFR 3.41).....\$ 40.00
Enclosed
XX Authorized to be charged to
deposit account

8. Deposit Account Number: 50-2587

9. Statement and signature.

To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Date

5/14/2004

D'Arcy H. Lorimer

Total number of pages including cover sheet, attachments, and document: / 2 /

05/20/2004 EDOOPER 00000136 502587 10845956

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40.00 DA

PATENT
REEL: 015339 FRAME: 0830

ASSIGNMENT

Whereas, we

INVENTOR
AND CITY

- (1) Alexander Driskill-Smith of Los Gatos, CA;
 (2) Hieu Lam of Milpitas, CA;
 (3) Kim Y. Lee of San Jose, CA,

have invented certain improvements in

TITLE

METHODS FOR IMPROVING POSITIONING PERFORMANCE OF ELECTRON BEAM LITHOGRAPHY ON MAGNETIC WAFERSDATES THAT
INVENTORS
SIGNED THE

and executed, respectively, a United States patent application therefore on

- (1) 5/10/04 (2) 5/11/04 (3) 5/16/04

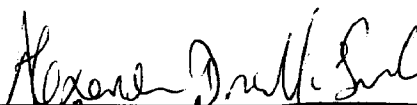
Whereas, **HITACHI GLOBAL STORAGE TECHNOLOGIES NETHERLANDS B.V.**, having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands (hereinafter called **HITACHI**), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefore;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to **HITACHI**, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the inventions set forth in said application to **HITACHI**, its successors and assigns; and we hereby agree that **HITACHI** may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by **HITACHI**.

Signed

CITY
DATE

(1) at SAN JOSE
 on May 11, 2004,


 Alexander Driskill-Smith

SIGNATURE
INVENTORCITY
DATE

(2) at San Jose
 on May 11, 2004,


 Hieu Lam

SIGNATURE
INVENTORCITY
DATE

(3) at San Jose
 on 5/14, 2004,


 Kim Y. Lee

SIGNATURE
INVENTOR